Lesker U
Vacuum Technology Series

University of Utah
Utah Nanofab

Workshop Topics Include:

Introduction to Vacuum Technology
Including:
- Adsorption, Desorption, Diffusion and Permeation
- Gas–Solid Interactions
- Flow Regimes
- Conductance
- Vacuum Pump Technologies, Pumping Speed and Pump Throughput
- Detecting leaks in vacuum systems

Physical Vapor Deposition and Thin Film Growth Models Including:
- Thermal & E-beam evaporation
- Sputtering by Direct Current (DC) & Rf
- Cathodic Arc Deposition
- Thin Film Growth Models
- The Structure Zone model(s)
- Stress in thin films
- Deposition rate and film characteristics

Course Schedule with approximate times

Monday, September 19th, 2016

- Introduction to Vacuum Technology 9:00 a.m. to 12:00pm.
- Physical Vapor Deposition and Thin Film Growth Models: 12:30pm – 4:00pm
- Lunch will be provided to registered attendees (please email amy.van@utah.edu to register)

Location: SMBB Auditorium, Room 2650, University of Utah Campus
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